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708

U.S. UTILITY Patent Application

PATENT NUMBER and
ISSUE DATE

APPL NUM 10004714	FILING DATE 12/05/2001	CLASS 257	SUBCLASS 306	GAU 2014	EXAMINER PERALTA
**APPLICANTS: Meikle Scott; Dean Trung;					
**CONTINUING DATA VERIFIED: THIS APPLICATION IS A DIV OF 09/537,238 03/28/2000 WHICH IS A DIV OF 08/977,800 11/25/1997 - <i>Division</i> WHICH IS A CON OF 08/667,907 06/12/1996 PAT 5,691,235 WHICH IS A CON OF 08/348,646 11/30/1994 ABN					
** FOREIGN APPLICATIONS VERIFIED:					
PG-PUB <input type="checkbox"/> DO NOT PUBLISH <input type="checkbox"/> RESCIND <input type="checkbox"/>					
Foreign priority claimed <input type="checkbox"/> yes <input type="checkbox"/> no 35 USC 119 conditions met <input type="checkbox"/> yes <input type="checkbox"/> no				ATTORNEY DOCKET NO 303.444US5	
Verified and Acknowledged Examiner's initials					
TITLE : Method of depositing tungsten nitride using a source gas comprising silicon					
U.S. DEPT. OF COMM/PAT & TM-PTO-4351 (Rev. 12-01)					

NOTICE OF ALLOWANCE MAILED		CLAIMS ALLOWED	
		Total Claims <input type="checkbox"/> Print Claim for O.G. <input type="checkbox"/>	
ISSUE FEE		DRAWING	
Amount Due	Date Paid	Sheets Drwg.	Figs. Drwg. <input type="checkbox"/> Print Fig. <input type="checkbox"/>
<input type="checkbox"/> TERMINAL DISCLAIMER		Application Examiner	
		PREPARED FOR ISSUE	
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